

Simulation of Topology Optimized Electrothermal Microgrippers

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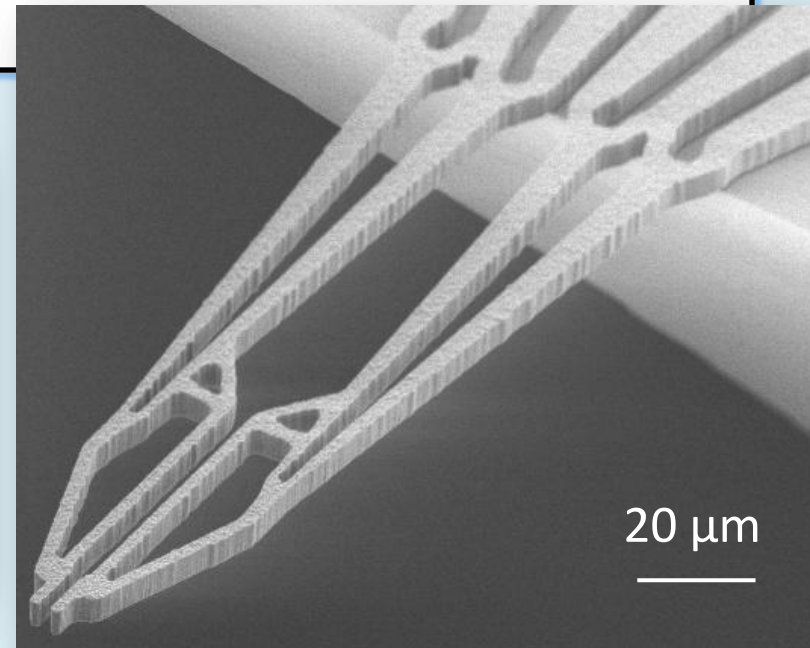
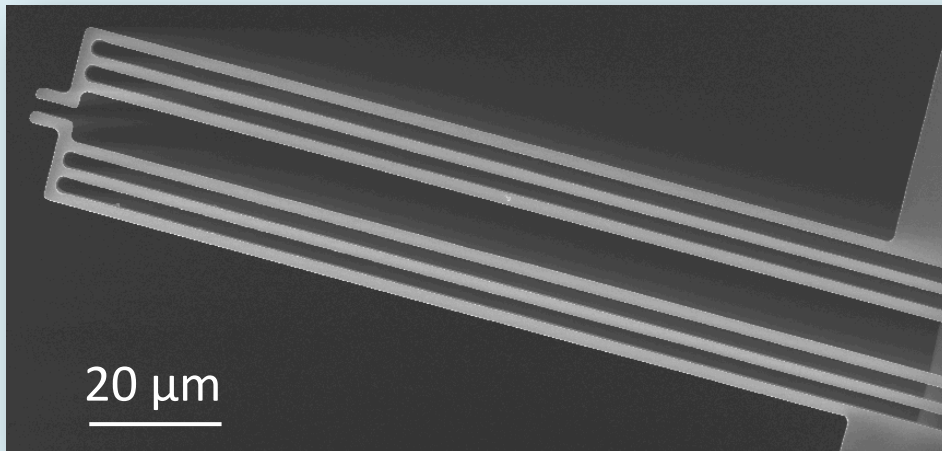
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Outline

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- › Motivation
- › The Microgripper Interface
- › The COMSOL Model
 - Geometry Settings
 - Subdomain Settings
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 - Mesh Settings
 - Solver Settings
- › Results & Discussion

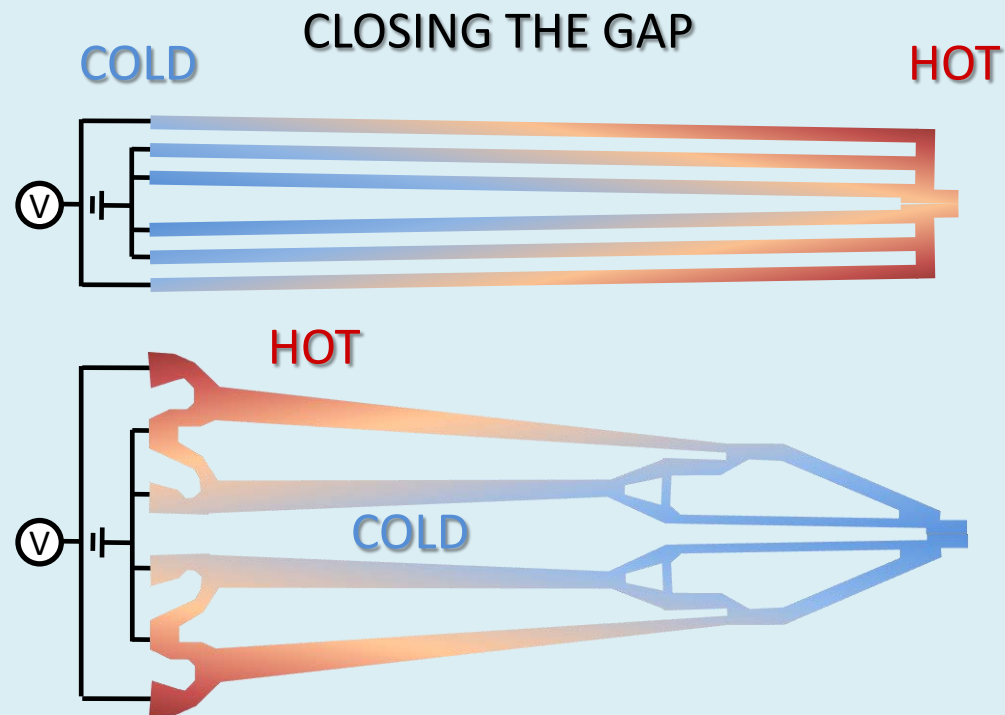
Electrothermal Microgrippers

- › Conventional Three-Beam Design
 - ☑ Compact & flexible design, easy to operate
 - ☒ Not strong enough
- › Topology Optimized Design
 - ☑ Flexible design, easy to operate
 - ☑ Much higher force at the same size!



Operation Principle

- › Same for both three-beam and topology optimized designs
- › Based on resistive heating
- › Open & close

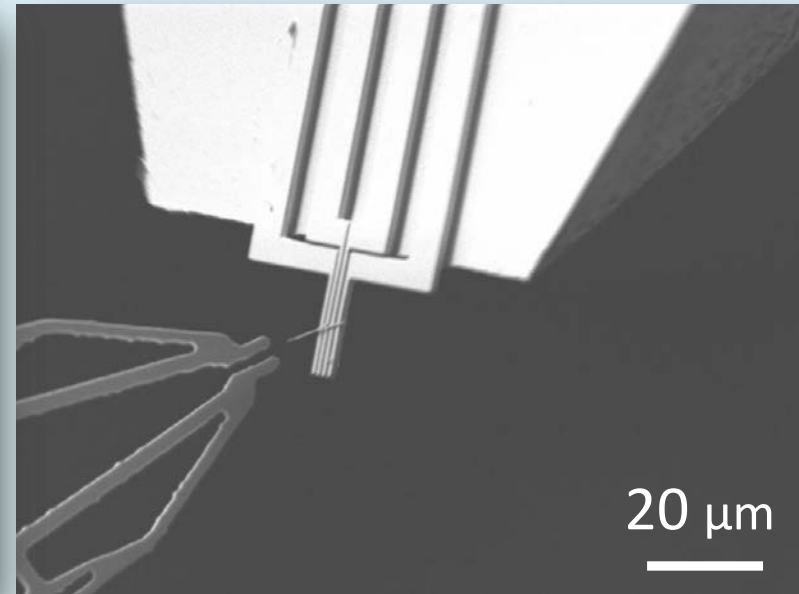
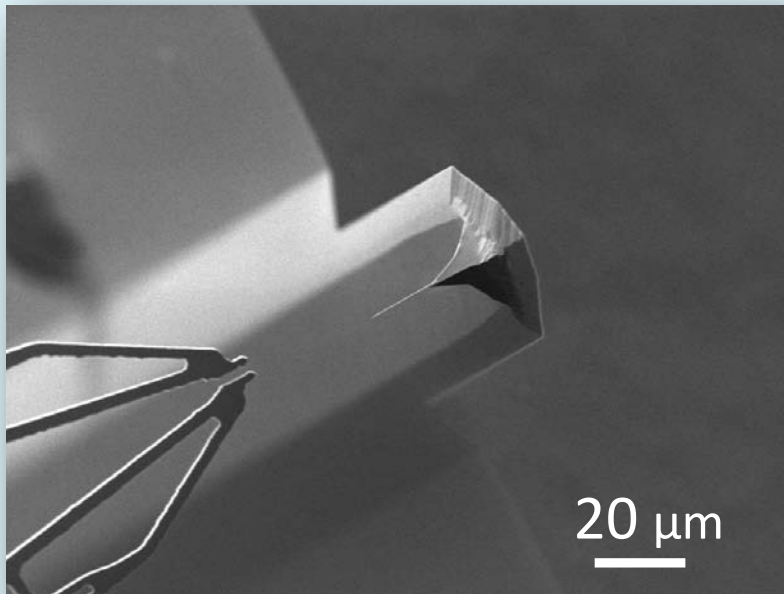


Nanomanipulation & Assembly

- › Basic nanomanipulation of carbon nanotubes/nanowires
 - On TEM grids for structural analysis
 - On electrodes for electrical characterization
- › Assembly of nano-devices
 - CNT/NanoBIT-enhanced AFM super-tips



*Collaboration
with V.Eichhorn*

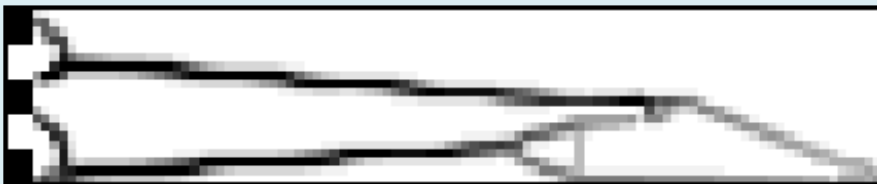


Motivation

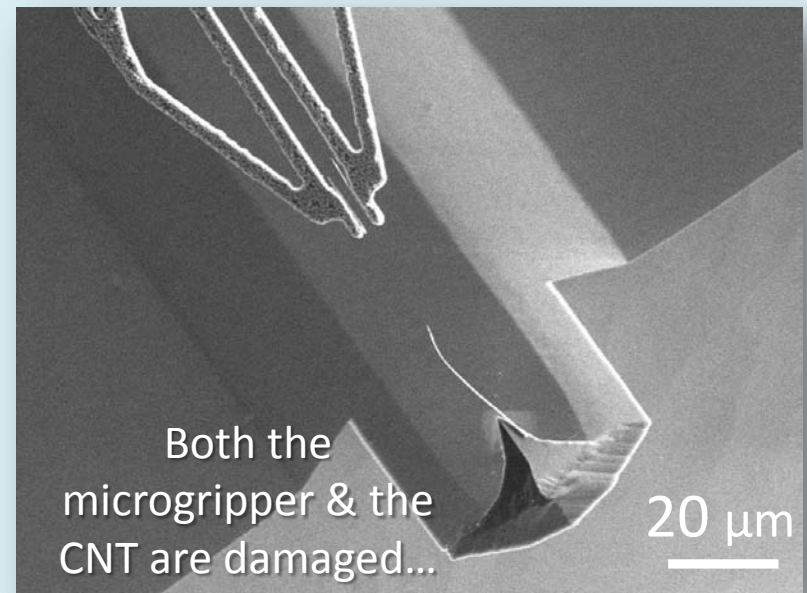
It is **important** to estimate...

- › The influence of design variations
 - During image processing after topology optimization
 - During various microfabrication steps
- › The operation temperature and the temperature at the end-effectors
- › The effect of the microgripper interface

Grey-scale output from the optimization algorithm...



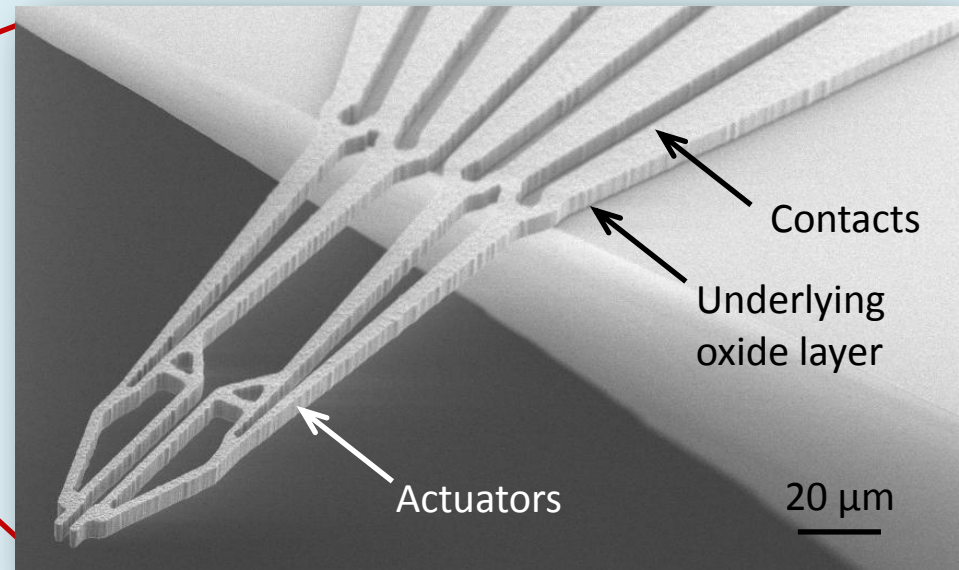
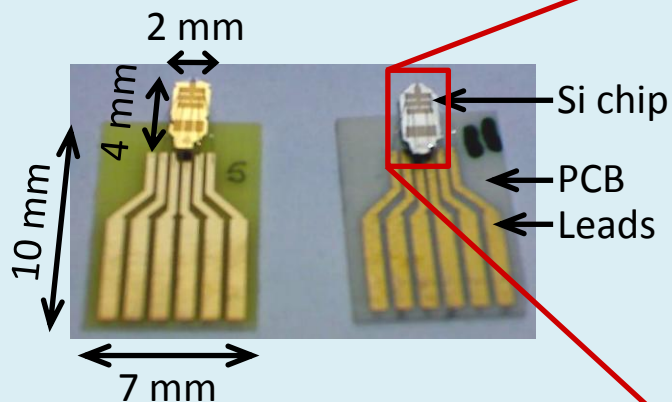
Improved binary image...



The Microgripper Interface

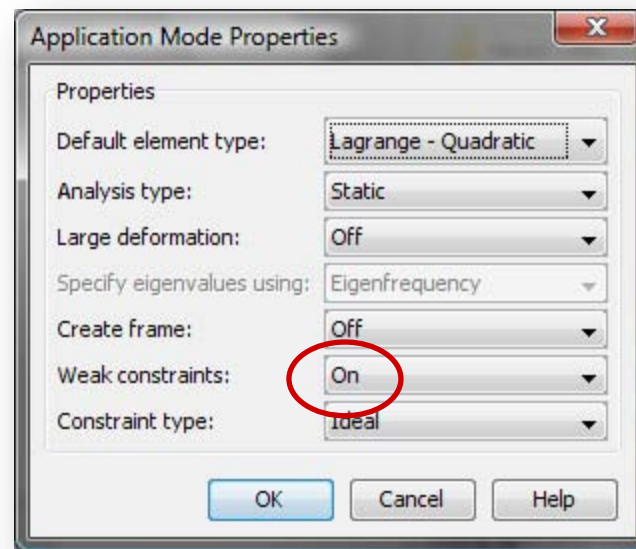
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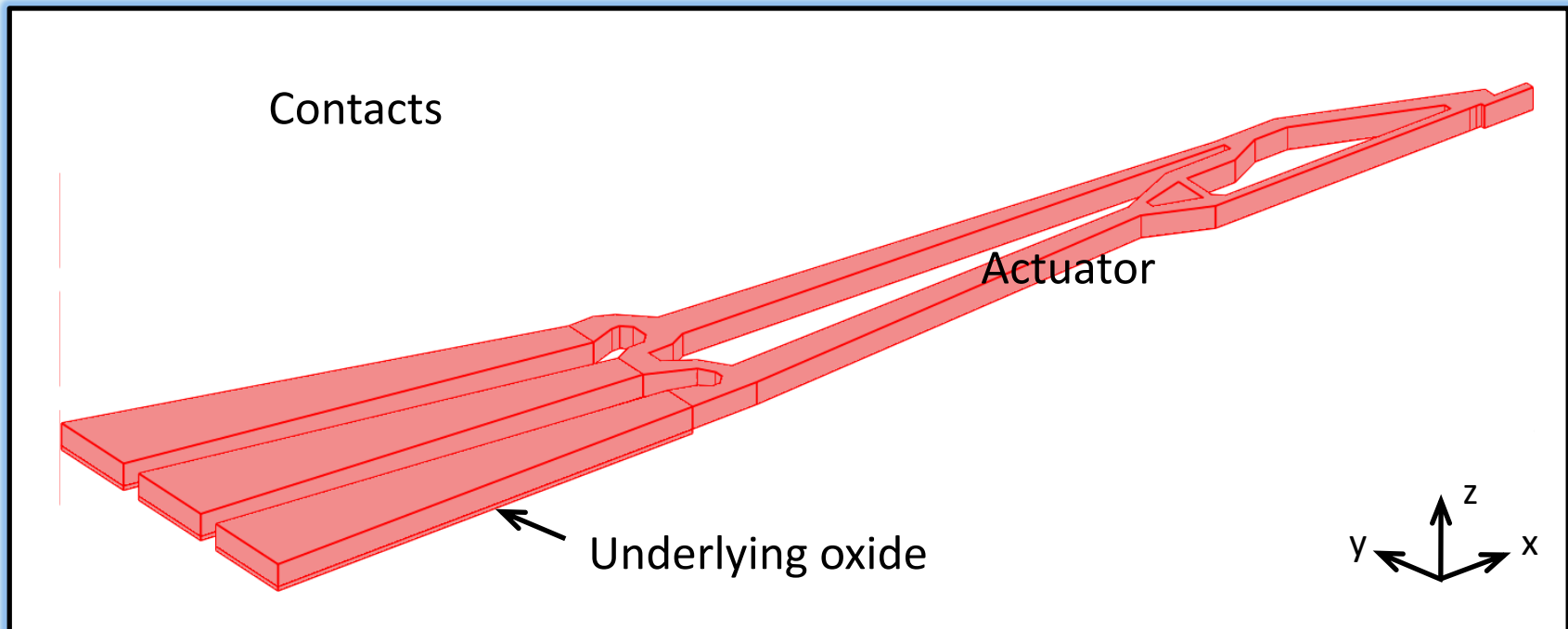
The COMSOL Model

- › 3D Model
- › Three application modes
 - Conductive Media (dc)
 - Heat Transfer by Conduction (ht)
 - Solid, Stress Strain (smsld) → Weak constraints on!



Geometry Settings

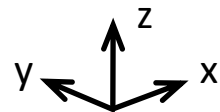
- › 2D CAD drawing from a DXF file
- › 3D model by extruding the geometry along the z-axis
 - Contact leads
 - 1 μm -thick oxide underneath



Subdomain Settings

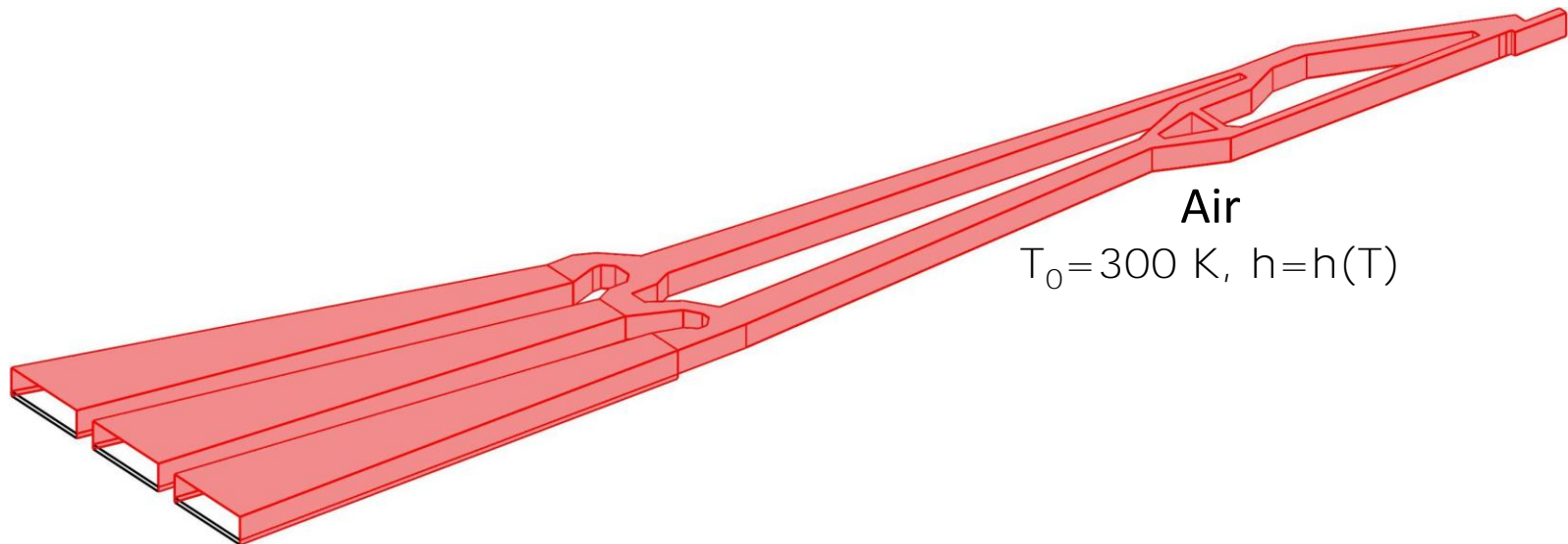
- › Silicon dioxide & polysilicon from the MEMS materials library
- › For polysilicon, $\alpha = \alpha(T)$, $\sigma = \sigma(T)$ and $k = k(T)$ (Geisberger 2003)
- › For all subdomains
 - Resistive heating
 - Thermal expansion

Polysilicon



Boundary Settings

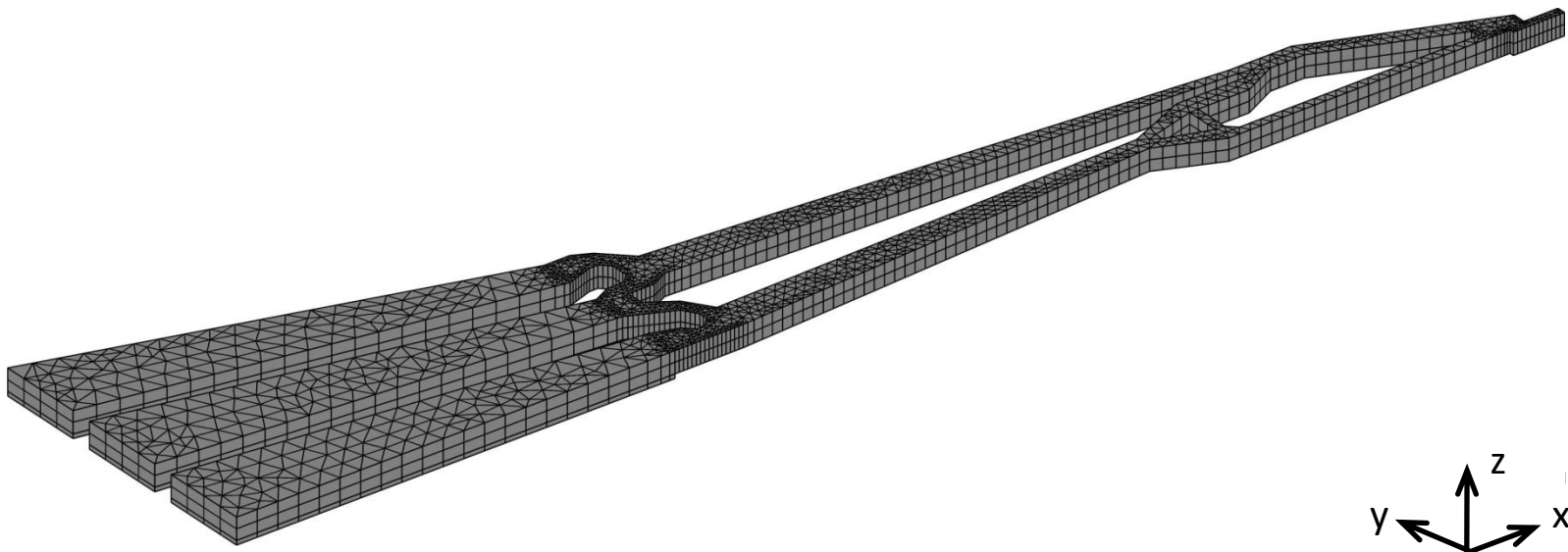
- › Electrical domain
- › Thermal domain
 - Fixed temperature underneath the oxide
 - Air convection, with $h = h(T)$ (Geisberger2003)
- › Mechanical Domain



Mesh Settings

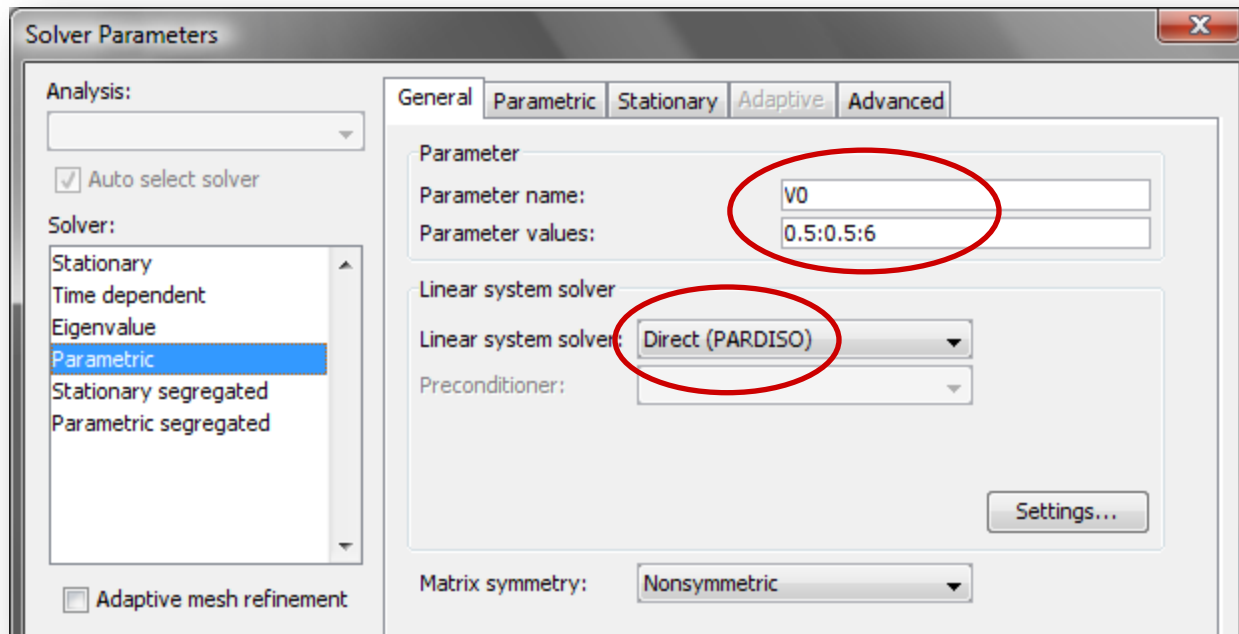
› Variable mesh density

1. Meshing the critical edges
2. Meshing the upper boundaries
3. Sweeping through all subdomains (multiple layers)



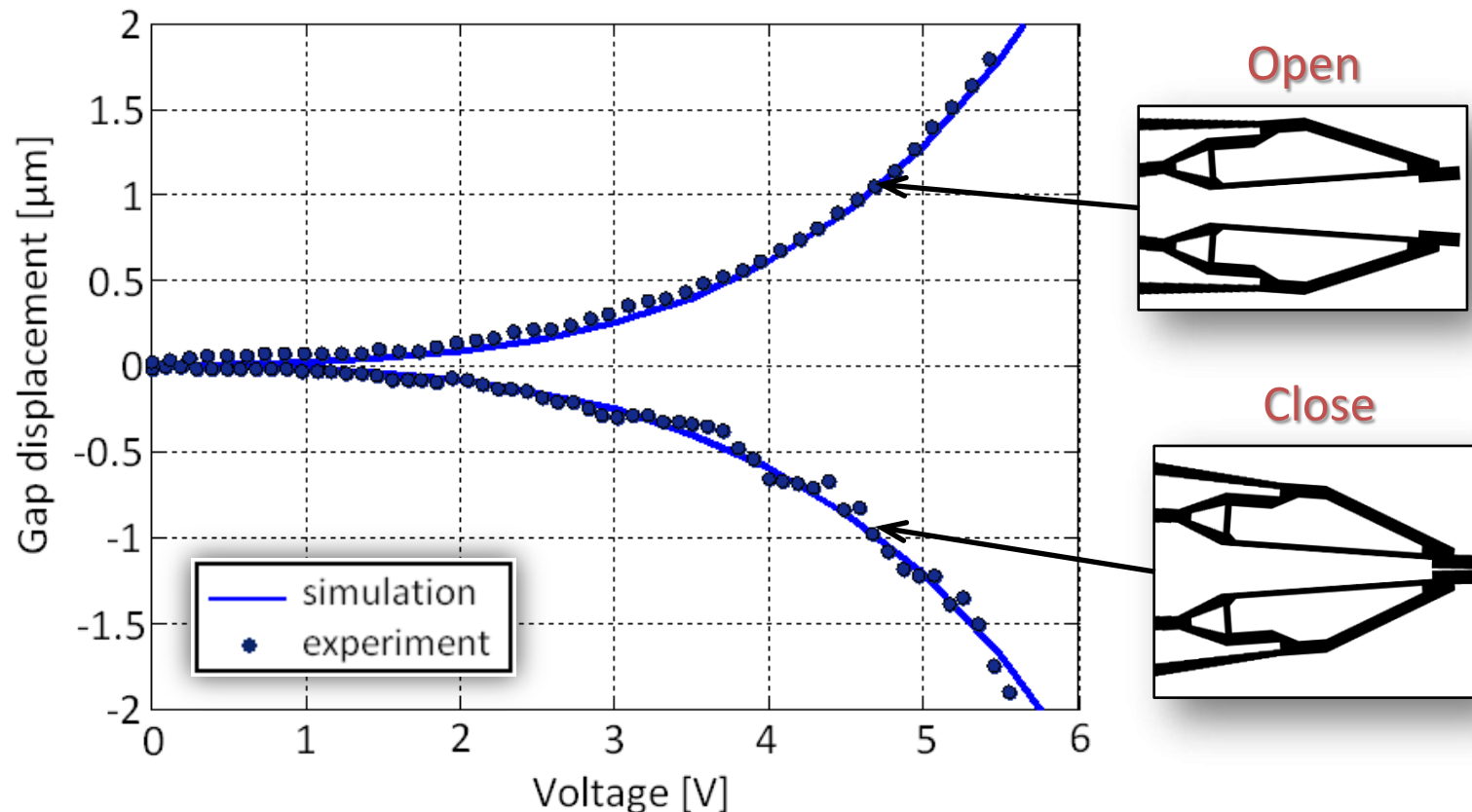
Solver Settings

- › Simulation of the actuation behavior
 - Parametric solver with default settings



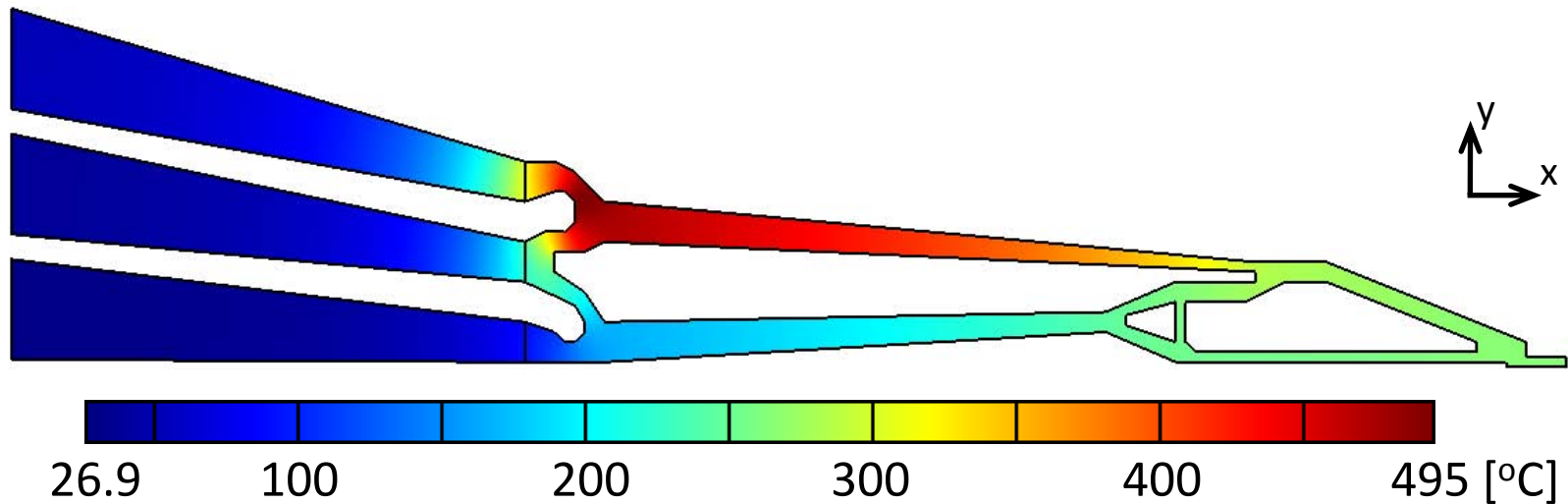
Displacement Results vs. Experiments

- › Actuation under an optical microscope at room temperature
- › Simultaneous filtering and image processing



Temperature Results

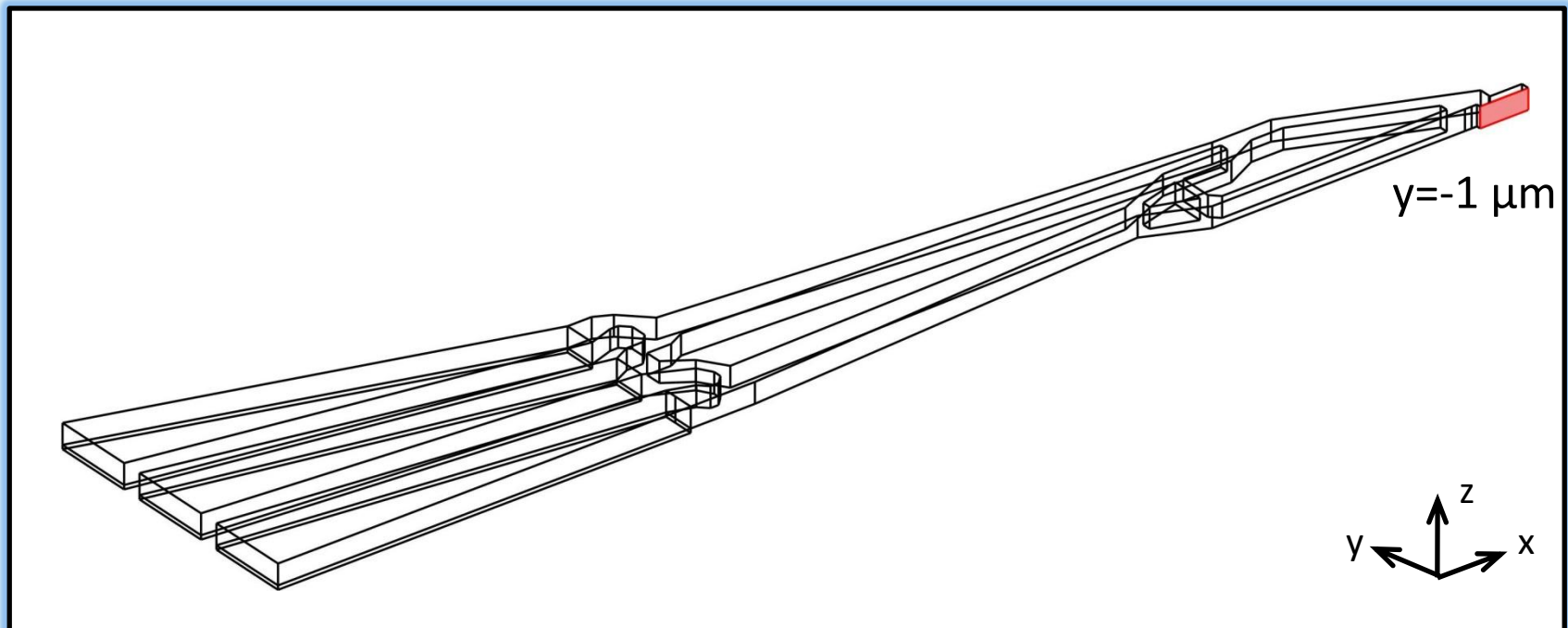
- › Temperature distribution within the actuator
 - Gap fully closed \rightarrow 1 μm -displacement, $V_0 = 5.6$ V
- › Ongoing Raman measurements agree with the profile!



Finding the In-plane Stiffness

› Settings:

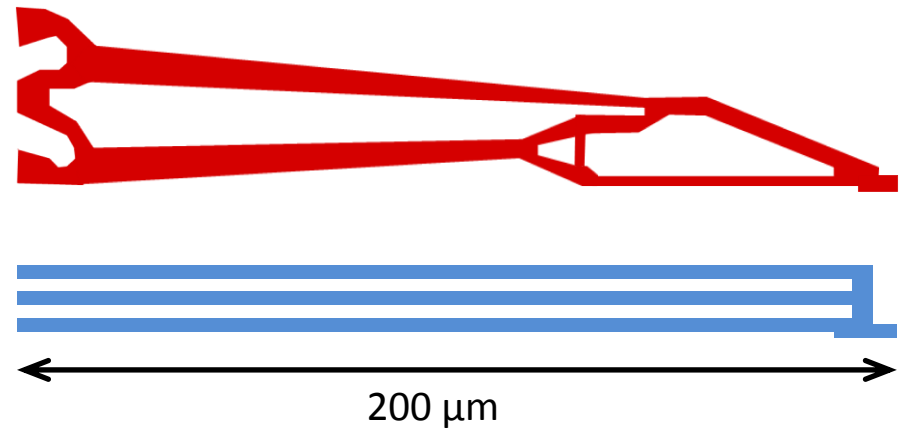
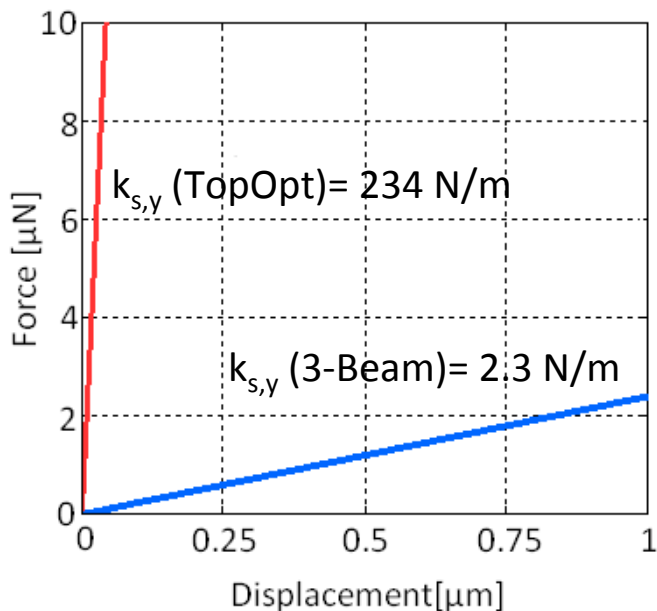
- Prescribed displacement at the end-effector boundary
- Solving **only** for the mechanical domain
- Integrating the force over the boundary



Stiffness Results

› Results:

- Conventional design: $k_{s,y} = 2.3 \text{ N/m}$
(Agrees well with force measurements...)
- Optimized design: $k_{s,y} = 234 \text{ N/m}$
- ☑ $\sim 10^2$ times improvement at the **same** size!



Acknowledgements

› EU Projects:

– NANOHAND

– NANORAC

 NanoHand •

NANORAC

› COMSOL A/S (Denmark):

– Lars Gregersen

– Thure Ralfs

THANK YOU FOR YOUR ATTENTION

QUESTIONS & COMMENTS?

Material Properties (I)

Temperature, T [K]	Thermal Conductivity, k [W/(m·K)]	CTE, α [K ⁻¹]
300	65.00	2.5×10^{-6}
400	53.75	3.1×10^{-6}
500	46.54	3.5×10^{-6}
600	40.00	3.8×10^{-6}
700	35.00	4.1×10^{-6}
800	32.08	4.3×10^{-6}

Electrical Conductivity, $\sigma = 1/\rho = \beta_1 + \beta_2 \cdot T^{\beta_3}$	
Coefficient	Value
β_1	2.6×10^{-3}
β_2	8.16×10^{-9}
β_3	1.946

Material Properties (II)

Temperature [K]	Heat Transfer Coefficient, h [W/(m ² ·K)]
300	1101.7
400	1214.3
500	1381.0
600	1520.7
700	1660.3
800	1799.9